Group Art Unit: 2183

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re application of:
 Mei, et al.

Serial No. 10/064,156

Filed: June 14, 2002

For: MODIFIED PHOTOLITHOGRAPHY MOVEMENT SYSTEM

Examiner: Unknown RECEIVED

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Technology Center 2100

<u>INFORMATION DISCLOSURE STATEMENT</u>

Commissioner For Patents Washington, D.C. 20231

Dear Sir:

In compliance with the duty of disclosure under 37 CFR §1.56, and in accordance with the practice under 37 CFR §1.97 and §1.98, the Examiner's attention is directed to the documents listed on the enclosed modified Form PTO-1449. No inference should be made that the cited references are in fact material, are in fact prior art, or that no better art exists. The cited patents are listed in numerical order and are not in any order based on their pertinence. Copies of the listed information are attached.

This Information Disclosure Statement is being filed within three months of the United States filing date or before the mailing date of a first Office Action on the merits. No certification or fee is required (37 CFR §1.97(b)).

The Commissioner is hereby authorized to charge any additional fees which may be required or credit any overpayment to Deposit Account 08-1394.

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Respectfully submitted,

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Registration No. 42,044

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Certi	ficate	Λf	Ma	iline	,

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to Commissioner For Patents, Washington, D.C.

20231 on <u>2. 5. 03</u>

B.E. Boyle

Printed Name

Signature Signature

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Examiner	Date	
Signature	Considered	

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

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